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PATENT
Atty. Dkt. No. AMAT/0827.C1/DISPLAY/AKT/RKK

AF
2814

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of:
Harshbarger, et al.

Serial No.: 10/052,878

Confirmation No.: 4040

Filed: November 2, 2001

For: Method of Depositing
Amorphous Silicon Based Films
Having Controlled Conductivity

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

§
§ Group Art Unit: 2814
§
§
§ Examiner: Ginette Peralta
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§

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on April 23, 2004, with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

4/23/04

Date

Signature

RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 25, 2004

In response to the Final Office Action dated February 25, 2004, having a shortened statutory period for response set to expire on May 25, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/ AMAT/0827.C1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 4 of this paper.